

Special Issue

Two-Dimensional Materials: Properties and Devices Applications

Message from the Guest Editors

The abundance of two-dimensional (2D) materials has provided tremendous research opportunities and led to extensive investigations of their unique electronic, optical, chemical, thermal and mechanical properties. Their atomic thickness, sizeable bandgaps and van der Waals layer coupling make them highly designable and manipulable for novel device applications. Along with the rapid development of controllable and scalable synthesis techniques of high-quality 2D materials and their heterostructures, devices with extraordinary performance have been designed and fabricated, including transistors, memories, spintronic devices, photodetectors, transducers and sensing devices. In this Special Issue, we aim to focus on the characterization and manipulations of 2D materials and their heterostructures for novel properties and device applications.

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